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TRANSMITTAL FORM

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Total Number of Pages in This Submission

Application Number 10/524.809

Filing Date 02/15/2005

First Named Inventor James S. Im

Art Unit 2822

Examiner Name

Attorney Docket Number A35416-PCT-USA (070050.2721)

ENCLOSURES (Check all that apply)

<input type="checkbox"/> Fee Transmittal Form	<input type="checkbox"/> Drawing(s)	<input type="checkbox"/> After Allowance Communication to TC
<input type="checkbox"/> Fee Attached	<input type="checkbox"/> Licensing-related Papers	<input type="checkbox"/> Appeal Communication to Board of Appeals and Interferences
<input type="checkbox"/> Amendment/Reply	<input type="checkbox"/> Petition	<input type="checkbox"/> Appeal Communication to TC (Appeal Notice, Brief, Reply Brief)
<input type="checkbox"/> After Final	<input type="checkbox"/> Petition to Convert to a Provisional Application	<input type="checkbox"/> Proprietary Information
<input type="checkbox"/> Affidavits/declaration(s)	<input type="checkbox"/> Power of Attorney, Revocation	<input type="checkbox"/> Status Letter
<input type="checkbox"/> Extension of Time Request	<input type="checkbox"/> Change of Correspondence Address	<input checked="" type="checkbox"/> Other Enclosure(s) (please identify below):
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Remarks

SIGNATURE OF APPLICANT, ATTORNEY, OR AGENT

Firm Name	Baker Botts LLP	Customer No.	21003
Signature			
Printed name	Paul A. Ragusa		
Date	10/11/2005	Reg. No.	38,587

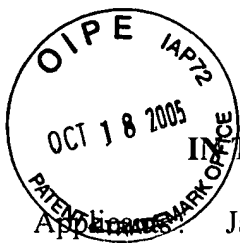
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This collection of information is required by 37 CFR 1.5. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.11 and 1.14. This collection is estimated to 2 hours to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: James Im Customer No.: 21003
Serial No. : 10/524,809 Examiner : Not yet assigned
Filed : 02/15/2005 Group Art Unit: 2822
For : Single-Shot Semiconductor Processing System And Method Having Various
Irradiation Patterns

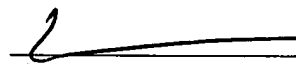
INFORMATION DISCLOSURE STATEMENT

I hereby certify that this paper is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

October 11, 2005
Date of Deposit

Paul A. Ragusa
Attorney Name

38,587
Patent Reg. No.


Signature

October 11, 2005
Date of Signature

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 C.F.R. §§ 1.56 and 1.97(b), applicants bring to the attention of the Examiner the documents listed on the attached Form PTO 1449 and respectfully request that the listed documents be considered by the Examiner and made of record in the above-captioned application. Copies of all U.S. Patents and Applications are not enclosed pursuant to the waiver of 37 CFR 1.98 (a)(2)(i) for all applications filed after June 30, 2003. However, copies of all of the other documents listed on the Form PTO-1449 are enclosed herewith.

This submission does not represent that a search has been made or that no better art exists and does not constitute an admission that the listed documents are material or constitute "prior art." If the Examiner applies the documents as prior art against any claim in the application and applicants determine that the cited documents do not constitute "prior art" under United States law, applicants reserve the right to present to the Office the relevant facts and law regarding the appropriate status of the documents.

Applicants further reserve the right to take appropriate action to establish the patentability of the disclosed invention over the listed documents, should the documents be applied against the claims of the present application.

This Information Disclosure Statement is being before the mailing of a First Office Action. Therefore, applicants believe no fee is due. If any additional fee is due, or if any overpayment has been made, the Commissioner is authorized to charge any such fee or credit any overpayment, to our Deposit Account No. 02-4377.

Respectfully submitted,

BAKER BOTTS L.L.P.

By: 

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Form PTO-1449 U.S. Department of Commerce
(REV. 2-82) Patent and Trademark Office

Atty. Docket No.
A35416-PCT-USA
(070050.2721)

Serial No.
10/524,809

**INFORMATION DISCLOSURE STATEMENT
BY APPLICANT**

(Use several sheets if necessary)

Applicant
James S. Im

Filing Date
02/15/2005

Group
2822

Examiner
Not yet assigned

U.S. PATENT DOCUMENTS

Exam. Initial.	No.	Document No.	Issue/Publication Date	Applicant(s)
	1	3632205	01/04/1972	Marcy
	2	4234358	11/18/1980	Celler et al.
	3	4309225	01/05/1982	Fan et al.
	4	4382658	05/10/1983	Shields et al.
	5	4456371	06/1984	Lin
	6	4639277	01/27/1987	Hawkins
	7	4691983	09/08/1987	Kobayashi et al.
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	10	4793694	12/27/1988	Liu
	11	4800179	01/1989	Mukai
	12	4855014	08/1989	Kakimoto et al.
	13	4870031	09/1989	Suguhara et al.
	14	4940505	07/1990	Schachameyer et al.
	15	4970546	11/1990	Suzuki et al.

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Examiner

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* Examiner: Initial citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Form PTO-1449 U.S. Department of Commerce (REV. 2-82) Patent and Trademark Office INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)	Atty. Docket No. A35416-PCT-USA (070050.2721)	Serial No. 10/524,809
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Exam. Initial.	No.	Document No.	Issue/Publication Date	Applicant(s)
	16	4977104	12/11/1990	Sawada et al.
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	21	5233207	08/1993	Anzai
	22	5285236	02/08/1994	Jain
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	31	5523193	06/1996	Nelson

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	32	5529951	06/1996	Noguchi et al.
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	36	5742426	04/1998	York
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	41	5893990	04/1999	Tanaka
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	43	6014944	01/18/2000	Russell et al.
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	46	6117752	09/12/2000	Suzuki.
	47	6120976	09/2000	Treadwell et al.
	48	6130009	10/2000	Smith et al.

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Exam. Initial.	No.	Document No.	Issue/Publication Date	Applicant(s)
	49	6130455	10/10/2000	Yoshinouchi
	50	6156997	12/2000	Yamazaki et al.
	51	6162711	12/19/2000	Ma et al.
	52	6169014	01/2001	McCulloch
	53	6172820	01/2001	Kuwahara.
	54	6177301	01/2001	Jung
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	65		6320227	11/2001	Lee et al.
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	67		6326186	12/2001	Park et al.
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	69		6333232	12/2001	Kunikiyo
	70		6368945	04/09/2002	Im
	71		6388146	05/14/2002	Onishi et al.
	72		6407012	06/18/2002	Miyasaka et al.
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	76		6511718	01/18/2003	Paz de Araujo et al.
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	78		6528359	03/2003	Kusumoto et al.
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	80		6573531	06/2003	Im et al.

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Exam. Initial.	No.	Document No.	Issue/Publication Date	Applicant(s)
	81	6621044	09/01/2003	Jain et al.
	82	6635554	10/2003	Im et al.
	83	6526585	03/04/2003	Hill
	84	20010001745	05/24/2001	Im et al.
	85	20010041426	11/15/2001	Im
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	88	RE33836	03/03/1992	Resor, III et al.
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	123	2003096489	05/22/2003	Im et al.
	124	2003119286	06/26/2003	Im et al.
	125	2005032249	02/10/2005	Im et al.
	126	2003029212	02/13/2003	Im
	127	2004061843	04/01/2004	Im
	128	2005034653	02/17/2005	Im et al.
	129	6563077	05/13/2003	Im

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Exam. Initial.	No.		Document No.	Issue/Publication Date	Applicant(s)
	130		6582827	06/24/2003	Im
	33		6830993	12/14/2004	Im et al.

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FOREIGN PATENT DOCUMENTS

Exam Initial	No.		Document No.	Publication Date	Country	Translation	
						Yes	No
	90		681316	08/11/1995	EP		
	91		1067593	10/01/2001	EP		
	92		655774	07/17/1996	EP		
	93		2338343	12/15/1999	GB		
	94		2338597	12/22/1999	GB		
	95		2338342	12/15/1999	GB		
	96		2283036	11/20/1990	JP		<u>No</u>
	97		6252048	09/09/1994	JP		<u>No</u>
	98		6283422	10/07/1994	JP		<u>No</u>
	99		7176757	07/14/1995	JP		<u>No</u>
	100		11064883	03/05/1999	JP		<u>No</u>
	101		04033327		JP		<u>No</u>
	102		2001023920	01/26/2001	JP		
	103		62181419	08/08/1987	JP		
	104		9824118	06/04/1998	WO		

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Exam Initial	No.		Document No.	Publication Date	Country	Translation	
						Yes	No
	105		9931719	06/24/1999	WO		<u>No</u>
	106		0014784	03/16/2000	WO		
	107		0118854	03/15/2001	WO		
	108		0118855	03/15/2001	WO		
	109		0171786	09/27/2001	WO		
	110		02031869	04/18/2002	WO		
	111		02086954	05/30/2002	WO		
	112		9745827	12/04/1997	WO		
	113		0242847	05/30/2002	WO		
	114		03046965	06/05/2003	WO		
	115		02086955	10/31/2002	WO		
	116		03018882	03/06/2003	WO		
	117		04017379	02/26/2004	WO		
	118		03084688	10/16/2003	WO		
	119		04017382	02/26/2004	WO		
	120		04017381	02/26/2004	WO		

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Exam Initial	No.		Document No.	Publication Date	Country	Translation	
						Yes	No
	121		04017380	02/26/2004	WO		
	122		04075263	08/19/2003	WO		

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Exam Initial	No.	OTHER DOCUMENTS (including Author, Title, Date, Pertinent Pages, Etc.)
	132	Im et al., "Controlled Super-Lateral Growth of Si Films for Microstructural Manipulation and Optimization", Phys. Stat. Sol. (a), vol. 166, p. 603 (1998).
	133	S.D. Brotherton et al., "Influence of Melt Depth in Laser Crystallized Poly-Si Thin Film Transistors," 82 J. Appl. Phys. 4086 (1997).
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	135	Im et al., "Single-Crystal Si Films for Thin-Film Transistor Devices," Appl. Phys. Lett., Vol 70 (25), p. 3434 (1997).
	136	Sposili et al., "Sequential Lateral Solidification of Thin Silicon Films on SiO ₂ ", Appl. Phys. Lett., vol. 69 (19), p. 2864 (1996).*
	137	Crowder et al., "Low-Temperature Single-Crystal Si TFT's Fabricated on Si Films processed via Sequential Lateral Solidification", IEEE Electron Device Letter, vol. 19 (8), p. 306 (1998).*
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	140	J. H. Jeon et al., "Two-step laser recrystallization of poly-Si for effective control of grain boundaries", Journal of Non Crystalline Solids, North-Holland Publishing Company, NL, vol. 266-269, May 2000, pp. 645-649.
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	143	K.H. Weiner et al., "Ultrashallow Junction Formation Using Projection Gas Immersion Laser Doping (PGILD)," A Verdant Technologies Technical Brief, Aug. 20, 1997.
	144	Hau-Riege C.S. et al., "The Effects Microstructural Transitions at Width Transitions on interconnect reliability," Journal of Applied Physics, June 15, 2000, vol. 87, no. 12, pp. 8467-8472
	145	McWilliams et al., "Wafer-Scale Laser Pantography: Fabrication of N-Metal-Oxide-Semiconductor Transistors and Small-Scale Integrated Circuits By Direct-Write Laser-Induced Pyrolytic Reactions," Applied Physics Letters, American Institute of Physics, New York, US, vol. 43, no. 10, Nov. 1983, pp. 946-948
	146	Mariucci et al., "Grain boundary location control by patterned metal film in excimer laser crystallized polysilicon," Proceedings of the Fifth International Conference on Polycrystalline Semiconductors, Schwabisch Gmund, Germany, Sept. 13-18, 1998, vol. 67-68, pp. 175-180
	147	Broadbent et al., "Excimer Laser Processing of Al-1%Cu/TiW Interconnect Layers," 1989 Proceedings, Sixth International IEEE VLSI Multilevel Interconnection Conference, Santa Clara, CA, June 12-13, 1989, pp. 336-345
	148	H.J. Kim and James S. Im, "Grain Boundary Location-Controlled Poly-Si Films for TFT Devices Obtained Via Novel Excimer Laser Process," Abstracts for Symposium of Materials Research Society, Nov.27 to Dec. 2, 1994, p. 230.
	149	S.D. Brotherton, "Polycrystalline Silicon Thin Film Transistors," 10 Semicond. Sci. Tech., pp. 721-738 (1995).
	150	H. Watanabe et al., "Crystallization Process of Polycrystalline Silicon by KrF Excimer Laser Annealing," 33 Japanese J. of Applied Physics Part 1--Regular Papers Short Notes & Review Papers, pp. 4491-98 (1994).
	151	E. Fogarassy et al., "Pulsed Laser Crystallization of Hydrogen-Free a-Si Thin Films for High-Mobility Poly-Si TFT Fabrication," 56 Applied Physics A--Solids and Surfaces, pp. 365-373 (1993).
	152	Y. Miyata et al., "Low-Temperature Polycrystalline Silicon Thin-Film Transistors for Large-Area Liquid Crystal Display," 31 Japanese J. of Applied Physics Part 1--Regular Papers Short Notes & Review Papers, pp. 4559-62 (1992).
	153	Im <i>et al.</i> , "Phase Transformation Mechanisms Involved in Excimer Laser Crystallization of Amorphous Silicon Films," Appl. Phys. Lett., Vol. 63 (14), p. 1969 (1993).

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	Examiner Not yet assigned	

Exam Initial	No.	OTHER DOCUMENTS (including Author, Title, Date, Pertinent Pages, Etc.)
	154	Im <i>et al.</i> , "On the Super Lateral Growth Phenomenon Observed in Excimer Laser-Induced Crystallization of Thin Si Films," Appl. Phys. Lett., Vol. 64 (17), p. 2303 (1994).
	155	Brochure from MicroLas Lasersystem, GmbH, "UV Optics Systems for Excimer Laser Based Micromaching and Marking". 1999.
	156	Ishida et al., "Ultra-shallow boxlike profiles fabricated by pulsed ultraviolet-laser doping process", J. Vac. Sci. Technol. B 12(1), p. 399-403, 1994. (No month).
	157	Yoshimoto, et al., "Excimer-Laser-Produced and Two-Dimensionally Position-Controlled Giant Si Grains on Organic SOG Underlayer", p. 285-286, AM-LCD 2000. No month.
	158	Ozawa et al., "Two-Dimensionally Position-Controlled Exicem-Laser-Crystallization of Silicon Thin Films on Glassy Substrate", Jpn. J. Appl. Phys. vol. 38, Part 1, No. 10, p. 5700-5705, (1999). No month.
	159	I.W. Boyd, Laser Processing of Thin Films and Microstructures, Oxidation, Deposition, and Etching of Insulators (Springer--Verlag Berlin Heidelber 1987).*
	160	N. Yamamuchi and R. Reif, Journal of Applied Physics, "Polycrystalline silicon thin films processed with silicon ion implantation and subsequent solid-phase crystallization: Theory, experiments, and thin-film transistor applications" -- April 1, 1994 -- Volume 75, Issue 7, pp. 3235-3257
	161	T. Noguchi, "Appearance of Single-Crystalline Properties in Fine-Patterned Si Thin Film Transistors (TFTs) by Solid Phase Crystallization (SPC)," Jpn. J. Appl. Phys. Vol. 32 (1993) L1584-L1587
	162	Ishihara et al., "A Novel Double-Pulse Exicem-Laser Crystallization Method of Silicon Thin-Films," Japanese Journal of Applied Physics, Publication Office Japanese Journal of Applied Physics, Tokyo, Japan, vol. 34, no. 8A, August 1995, pp. 3976-3981
	163	Kim, H. J., "Excimer-Laser-Induced Crystallization of Amorphous Silicon Thin Films", Ph. D. Dissertation Abstract, Columbia University, 1996.*

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Examiner

Date Considered

* Examiner: Initial citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.